

213345US-2 CONT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF: :  
Kanefumi NAKAHARA ET AL. : EXAMINER:  
SERIAL NO.: NEW APPLICATION :  
FILED: HEREWITH : GROUP ART UNIT:  
FOR: EXPOSURE APPARATUS, LITHOGRAPHY  
SYSTEM AND CONVEYING METHOD,  
AND DEVICE MANUFACTURING METHOD  
AND DEVICE

PRELIMINARY AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

Prior to examination on the merits, please amend this application as follows:

IN THE SPECIFICATION

Please amend the specification as shown in the marked-up copy following this amendment.

Please replace the paragraph beginning on page 1, lines 7-11, with the following:

CROSS REFERENCE TO RELATED APPLICATION

This is a continuation of International Application PCT/JP00/01075, with an international filing date of February 25, 2000, the entire content of which being hereby incorporated herein by reference, which was not published in English.

Consequently, an action on the merits is earnestly solicited.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



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(OSMMN 11/98)

A handwritten signature in black ink, appearing to read 'J. Maier', written over the printed name.

Gregory J. Maier  
Attorney of Record  
Registration No. 25,599

James D. Hamilton  
Registration No. 28,421

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Marked-Up Copy
Serial No: <u>New App</u>
Amendment Filed on: <u>8-24-01</u>

IN THE SPECIFICATION

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